



IFW

PATENT
Docket No. 20063/OF03P193

**IN THE UNITED STATES PATENT
AND TRADEMARK OFFICE**

Applicant(s):

Ji Myong LEE

U.S. Serial No.: 10/733,067

For: "Apparatus and Methods of
Chemical Mechanical Polishing"


Filed: 12/11/2003

Group Art Unit: 2812

Examiner: Not Yet Assigned

) I hereby certify that this paper and the
) documents referred to as enclosed
) therewith are being deposited with the
) United States Postal Service as first
) class mail, postage prepaid, in an
) envelope addressed to Commissioner
) for Patents, P.O. Box 1450,
) Alexandria, Virginia 22313-1450 on
) this date:

June 24, 2005



Mark C. Zimmerman
) Attorney for Applicant(s)
) Registration No. 44,006

STATUS LETTER

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Sir:

Kindly advise when an Office action can be expected in the above-referenced
matter.

Respectfully submitted,

HANLEY, FLIGHT & ZIMMERMAN, LLC
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June 24, 2005

By:



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